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APPLICANTS

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** CONTINUING DATA ***** *Verified Verified*
 This application is a CIP of 10/278,992 10/24/2002
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** FOREIGN APPLICATIONS ***** *Verified Verified*
 REPUBLIC OF KOREA 2003-10159 02/18/2003
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Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 (a-d) conditions met <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance Verified and Acknowledged	<i>[Signature]</i> Examiner's Signature	<i>[Initials]</i> Initials	STATE OR COUNTRY KOREA, REPUBLIC OF	SHEETS DRAWING 8	TOTAL CLAIMS 25	INDEPENDENT CLAIMS 2
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TITLE
 Method of forming a silicon oxide layer in a semiconductor manufacturing process

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